

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional) KASA:019A

SERIAL NO.: NEW APPLICATION

APPLICANT(S) Tatsutoshi SUZUKI

FILING DATE: April 21, 2004

Group Art Unit

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
99L	US	5,921,855	7/99	Osterheld et al.	451	527	
99L	US	5,984,769	11/99	Bennett et al.	451	527	
99L	US	6,241,585	6/01	White	451	41	
99L	US	6,572,445	6/03	Laursen	451	10	
99L	US	6,561,891	5/03	Eppert, Jr. et al.	451	530	
99L	US	6,238,271	5/01	Cesna	451	41	
99L	US	5,398,458	3/95	Henriksen et al.	125	13:01	
99L	US	6,641,471	11/03	Pinheiro et al.	451	526	
99L	US	6,602,436	8/03	Mandigo et al.	216	88	

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
EEC	JP	11-70463	3/99	JAPAN (English Abst.)			X	
EEC	JP	47-16044	6/72	JAPAN (Concise Explanation)			X	
EEC	JP	63-22002	6/88	JAPAN (Concise Explanation)			X	
EEC	JP	2000-94303	4/00	JAPAN (English Abst.)			X	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

99L			The Science of CMP; August 20, 1997; pages 113-119; Chapter 4, Part III "Structure and Feature of the polishing pad".				
EXAMINER			DATE CONSIDERED 4/12/05				

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 509; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.